

Publikationen

- (2019): Analysis of residual errors during computer controlled polishing. In: EOS Optical Technologies: Conference on Manufacturing, Tolerancing and Testing of Optical Systems (MOS) – Session 7: Plenary Session, München.
- (2018): Model based error separation of power spectral density artefacts in wavefront measurement. In: SPIE Optical Engineering + Applications Conference on Interferometry XIX, San Diego, CA, USA.
- (2018): Model based error separation of power spectral density artefacts in wavefront measurement. In: Proceedings of SPIE 10749 (SPIE Optical Engineering + Applications Conference on Interferometry XIX [August 19-23, 2018; San Diego, CA, USA]). DOI: 10.1117/12.2321106.
- (2018): Contribution of the phase transfer function of extended measurement cavities to mid spatial frequencies and the overall error budget. In: Proceedings of SPIE 10829 (Fifth European Seminar on Precision Optics Manufacturing [April 10-11, 2018; Teisnach]). DOI: 10.1117/12.2318711.
- (2018): Tilted wave interferometry for testing large surfaces. In: Proceedings of SPIE 10829 (Fifth European Seminar on Precision Optics Manufacturing [April 10-11, 2018; Teisnach]). DOI: 10.1117/12.2318573.
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- (2017): Contribution of the phase transfer function of extended measurement cavities to mid spatial frequencies and the overall error budget. In: Fifth European Seminar on Precision Optics Manufacturing, Teisnach.
- (2017): Parametrization of a Subaperture Polishing Tool - Analysis of the Path Tests. In: Optical Fabrication and Testing part of Optical Design and Fabrication: 9-13 July 2017, Denver, Colorado, United States, Washington, D.C., USA.
- (2017): Yet one more dwell time algorithm. In: Proceedings of SPIE 10326 (Fourth European Seminar on Precision Optics Manufacturing, 1032601 [April 4th-5th 2017, Teisnach]). DOI: 10.1117/12.2270540.
- (2017): Polishing tool and the resulting TIF for three variable machine parameters as input for the removal simulation. In: Proceedings of SPIE 10326 (Fourth European Seminar on Precision Optics Manufacturing, 1032601 [April 4th-5th 2017, Teisnach]). DOI: 10.1117/12.2267415.
- (2015): Surface errors in the course of machining precision optics. In: Proceedings of SPIE Volume 9575, Optical Manufacturing and Testing XI (Aug 27th 2016, San Diego, CA). DOI: 10.1117/12.2189991.